

Equipment Front End Module EFEM



EFEM320-D01

SEMI S2(EFEM320 Series) APPROVED

Supports 8"SMIF



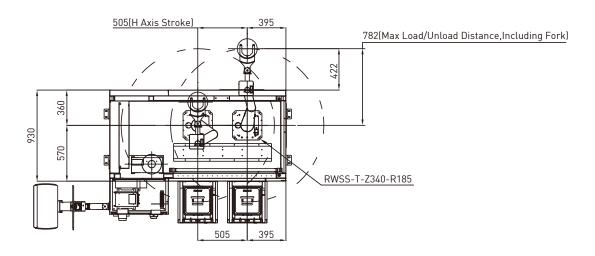
Outer Dimensions / Working Range

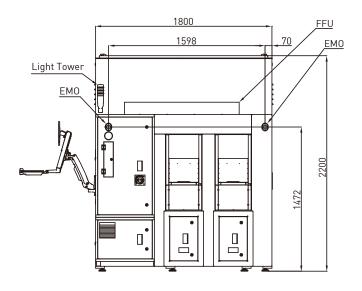
Features

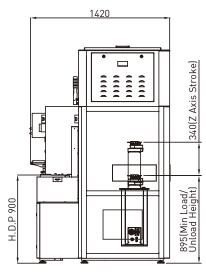
- Supports bar code, label and character recognition, complete tracking of the production process.
- Provides real-time video monitoring.
- Micro-environmental control such as high-efficiency purification and static elimination to ensure there is no contamination during transfer.
- An automatic pressure control system detects ambient pressure and adjusts the fan speed to maintain the set value.
- Supports customized wafer or other substrate handling requirements.

Item	Specification
Number of Ports	2 Ports
Robot Model	RWSS-T-Z340-D5R185
Reach	422mm
Wafer	8" (200mm), warpage ±1mm, thickness 500~1000μm
Repeatability	±0.1mm
Dimensions	1420mm X 1800mm X 2200mm
Cleanliness	Class1 @ 0.12μm
Power Supply	1 phase, 220VAC, 25A
Flow	Positive Pressure 100L/min, Negative Pressure 50L/min
Optional Accessories [Note 1]	Wafer ID Reader Bar Code Reader RFID Tag Reader E84 Module Static Eliminator SECS/GEM Communication [Note 2]

^{*} Note: 1. Optional Accessories not included.







EFEM320-D02

SEMI S2(EFEM320 Series) APPROVED

Supports 8", 12" WAFER



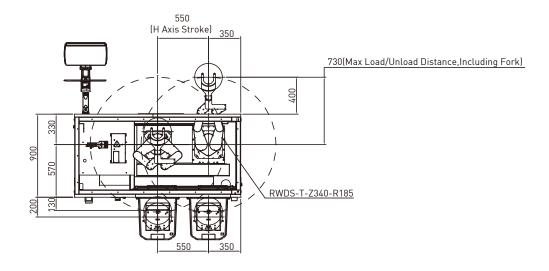
Outer Dimensions / Working Range

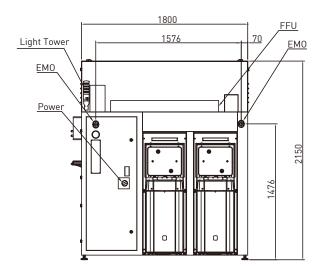
Features

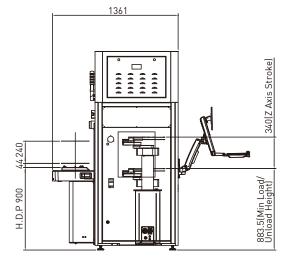
- Supports bar code, label and character recognition, complete tracking of the production process.
- Provides real-time video monitoring.
- Micro-environmental control such as high-efficiency purification and static elimination to ensure there is no contamination during transfer.
- An automatic pressure control system detects ambient pressure and adjusts the fan speed to maintain the set value.
- Supports customized wafer or other substrate handling requirements.

Item	Specification
Number of Ports	2 Ports
Robot Model	RWDS-T-Z340-D5R185
Reach	400mm
Wafer	8"(200mm), warpage \pm 1mm, thickness 500~1000 μ m; 12"(300mm), warpage \pm 1mm, thickness 650~1200 μ m
Repeatability	±0.1mm
Dimensions	1361mm X 1800mm X 2150mm
Cleanliness	Class1 @ 0.12μm
Power Supply	1 phase, 220VAC, 25A
Flow	Positive Pressure 100L/min, Negative Pressure 50L/min
Optional Accessories [Note 1]	Wafer ID Reader Bar Code Reader RFID Tag Reader E84 Module Static Eliminator SECS/GEM Communication (Note 2)

^{*} Note: 1. Optional Accessories not included.







EFEM220-D03

Supports 6", 8" WAFER



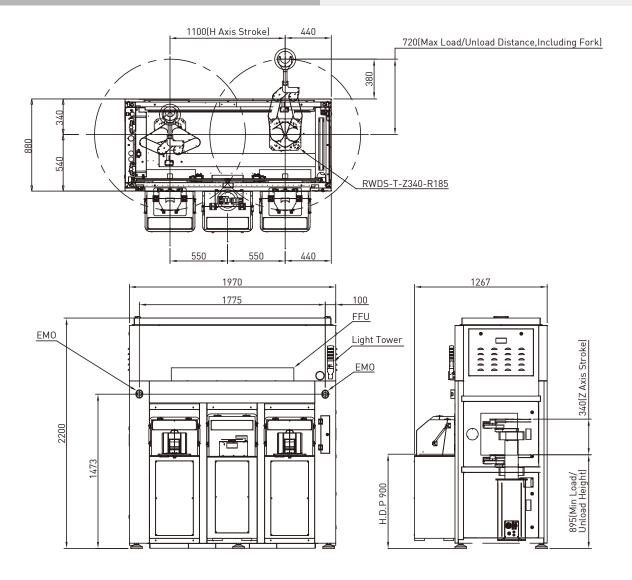
Outer Dimensions / Working Range

Features

- Supports bar code, label and character recognition, complete tracking of the production process.
- Provides real-time video monitoring.
- Micro-environmental control such as high-efficiency purification and static elimination to ensure there is no contamination during transfer.
- An automatic pressure control system detects ambient pressure and adjusts the fan speed to maintain the set value.
- Supports customized wafer or other substrate handling requirements.
- Comply with SEMI S2 design standard.

Item	Specification
Number of Ports	2 Ports
Robot Model	RWDS-T-Z340-D5R185
Reach	380mm
Wafer	6"(150mm), warpage \pm 1mm, thickness 400~600 μ m; 8"(200mm), warpage \pm 1mm, thickness 500~1000 μ m
Repeatability	±0.1mm
Dimensions	1267mm X 1970mm X 2200mm
Cleanliness	Class1 @ 0.12μm
Power Supply	1 phase, 220VAC, 25A
Flow	Positive Pressure 100L/min, Negative Pressure 50L/min
Optional Accessories [Note 1]	Wafer ID Reader Bar Code Reader RFID Tag Reader E84 Module Static Eliminator SECS/GEM Communication (Note 2)

^{*} Note: 1. Optional Accessories not included.



EFEM420-D04

Supports 8", 12" WAFER AND 8", 12" FRAME



Outer Dimensions / Working Range

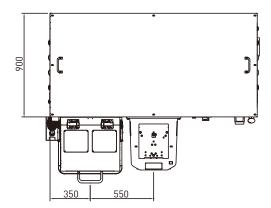


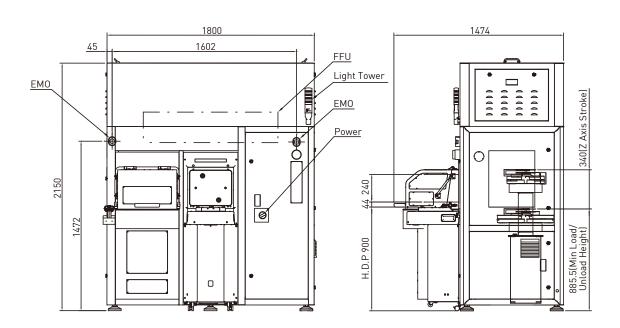
- Supports bar code, label and character recognition, complete tracking of the production process.
- Provides real-time video monitoring.
- Micro-environmental control such as high-efficiency purification and static elimination to ensure there is no contamination during transfer.
- An automatic pressure control system detects ambient pressure and adjusts the fan speed to maintain the set value.
- Supports customized wafer or other substrate handling requirements.
- Comply with SEMI S2 design standard.

Item	Specification
Number of Ports	2 Ports
Robot Model	RWDS-T-Z340-D5R185 (Upper arm vacuum module, lower arm clamping module needs to be replaced with corresponding sizes.)
Wafer	8" (200mm), warpage ± 1 mm, thickness 500 ~ 1000μ m; 12 "(300 mm), warpage ± 1 mm, thickness 650 ~ 1200μ m
Iron Frame	200/300mm, warpage \pm 1mm, thickness 1600 μ m
Repeatability	±0.1mm
Dimensions	1474mm X 1800mm X 2150mm
Cleanliness	Class1 @ 0.12µm
Power Supply	1 phase, 220VAC, 25A
Flow	Positive Pressure 100L/min, Negative Pressure 50L/min
Optional Accessories [Note 1]	Wafer ID Reader Bar Code Reader RFID Tag Reader E84 Module Static Eliminator SECS/GEM Communication (Note 2)

^{*} Note: 1. Optional Accessories not included.

 $2. \ \mathsf{SECS/GEM} \ \mathsf{to} \ \mathsf{be} \ \mathsf{developed} \ \mathsf{by} \ \mathsf{local} \ \mathsf{system} \ \mathsf{integrators} \ \mathsf{and} \ \mathsf{software} \ \mathsf{company}.$





EFEM320-D06

SEMI S2(EFEM320 Series) APPROVED

Supports 12" WAFER AND 12" METAL CARRIER



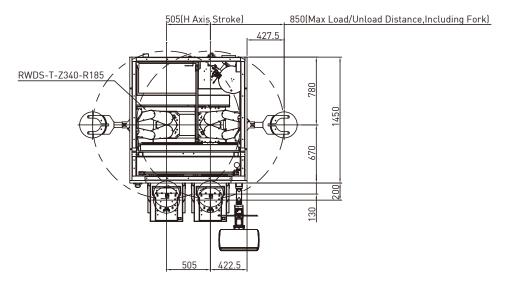
Outer Dimensions / Working Range

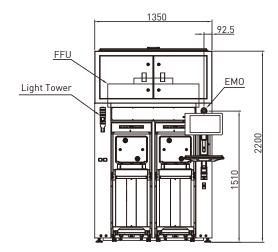
Features

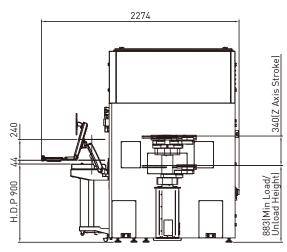
- Supports bar code, label and character recognition, complete tracking of the production process.
- Provides real-time video monitoring.
- Micro-environmental control such as high-efficiency purification and static elimination to ensure there is no contamination during transfer.
- An automatic pressure control system detects ambient pressure and adjusts the fan speed to maintain the set value.
- Supports customized wafer or other substrate handling requirements.

Item	Specification
Number of Ports	2 Ports
Robot Model	RWDS-T-Z340-03R185
Reach	427.5mm
Wafer	12"(300mm), warpage ±1mm, thickness 650~1200μm
Iron Frame	300mm, warpage ±1mm, thickness 1600μm
Repeatability	±0.1mm
Dimensions	2274mm X 1350mm X 2200mm
Cleanliness	Class1 @ 0.12μm
Power Supply	1 phase, 220VAC, 25A
Flow	Positive Pressure 100L/min, Negative Pressure 50L/min
Optional Accessories [Note 1]	Wafer ID Reader Bar Code Reader RFID Tag Reader E84 Module Static Eliminator SECS/GEM Communication (Note 2)

^{*} Note: 1. Optional Accessories not included.







EFEM120-D07

Supports 8", 12" FRAME



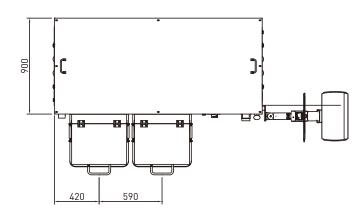
Outer Dimensions / Working Range

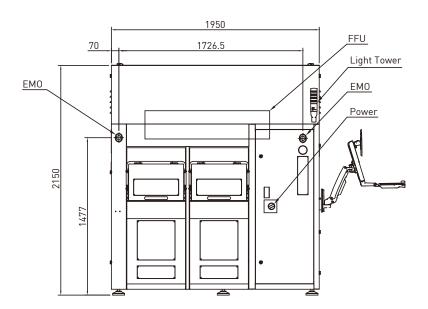
Features

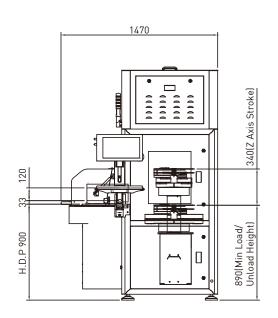
- Supports bar code, label and character recognition, complete tracking of the production process.
- Provides real-time video monitoring.
- Micro-environmental control such as high-efficiency purification and static elimination to ensure there is no contamination during transfer.
- An automatic pressure control system detects ambient pressure and adjusts the fan speed to maintain the set value.
- Supports customized wafer or other substrate handling requirements.
- Comply with SEMI S2 design standard.

ltem	Specification
Number of Ports	2 Ports
Robot Model	RWDS-T-Z340-03R185 (Clamping module needs to be replaced with corresponding size.)
Iron Frame	200/300mm, warpage ± 1 mm, thickness 1600 μ m
Repeatability	±0.1mm
Dimensions	1470mm X 1950mm X 2150mm
Cleanliness	Class1 @ 0.12μm
Power Supply	1 phase, 220VAC, 25A
Flow	Positive Pressure 100L/min, Negative Pressure 50L/min
Optional Accessories [Note 1]	Wafer ID Reader Bar Code Reader RFID Tag Reader E84 Module Static Eliminator SECS/GEM Communication (Note 2)

^{*} Note: 1. Optional Accessories not included.







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